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**OLIFF & BERRIDGE, PLC**

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ATTORNEYS AT LAW

**Application Data Sheet****Applicant Information**

Applicant Authority type::	Inventor
Primary Citizenship Country::	Japan
Status::	Full Capacity
Given Name::	Masakazu
Family Name::	SATO
City of Residence::	Fukushima
Country of Residence::	Japan

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Applicant Authority Type::	Inventor
Primary Citizenship Country::	Japan
Status::	Full Capacity
Given Name::	Masato
Family Name::	ONISHI
City of Residence::	Fukushima
Country of Residence::	Japan

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**Correspondence Information**

Correspondence Customer Number::	25944
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**Application Information**

Application Type::	National Phase
Subject Matter::	Utility
CD-ROM or CD-R::	None
Title::	METHOD OF EVALUATING SHAPE OF SEMICONDUCTOR WAFER AND APPARATUS FOR EVALUATING SHAPE OF SEMICONDUCTOR WAFER
Attorney Docket Number::	122035
Total Drawing Sheets::	8
Small Entity::	No

**Representative Information**

James A. Oliff, Reg. No. 27,075  
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<b>Domestic Priority Information</b>			
Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This Application is a	National Stage of	PCT/JP03/07320	06/10/2003
<b>Foreign Priority Information</b>			
Country::	Application Number::	Filing Date::	Priority Claimed::
Japan	2002-173268	06/13/2002	Yes
<b>Assignee Information</b>			
Assignee Name::		SHIN-ETSU HANDOTAI CO., LTD.	
Street of mailing address::		4-2, Marunouchi 1-chome,	
City of mailing address::		Chiyoda-ku,	
State or Province of mailing address::		Tokyo,	
Country of mailing address::		Japan	